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Commissioner for Patents  
P.O. Box 1450  
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On 10-10-05

TOWNSEND and TOWNSEND and CREW LLP

By: *Linda Shaffer*



**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of:

Di Gao et al.

Application No.: 10/613,508

Filed: July 3, 2003

For: SELECTIVE ETCHING OF  
SILICON CARBIDE FILMS

Customer No.: 20350

Confirmation No. 4814

Examiner: David E. Graybill

Technology Center/Art Unit: 2822

RESPONSE TO OFFICE  
COMMUNICATION

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

In response to the Office communication mailed September 9, 2005, Applicants elect the following species for purposes of examination: (1) silicon dioxide layer, claims 1-6, 10, 13-24 and 31-32; and (2) hydrogen bromide etch chemistry, claims 1-6, 10, 13-24 and 31-32.

**Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this paper.

**Remarks/Arguments** begin on page 7 of this paper.